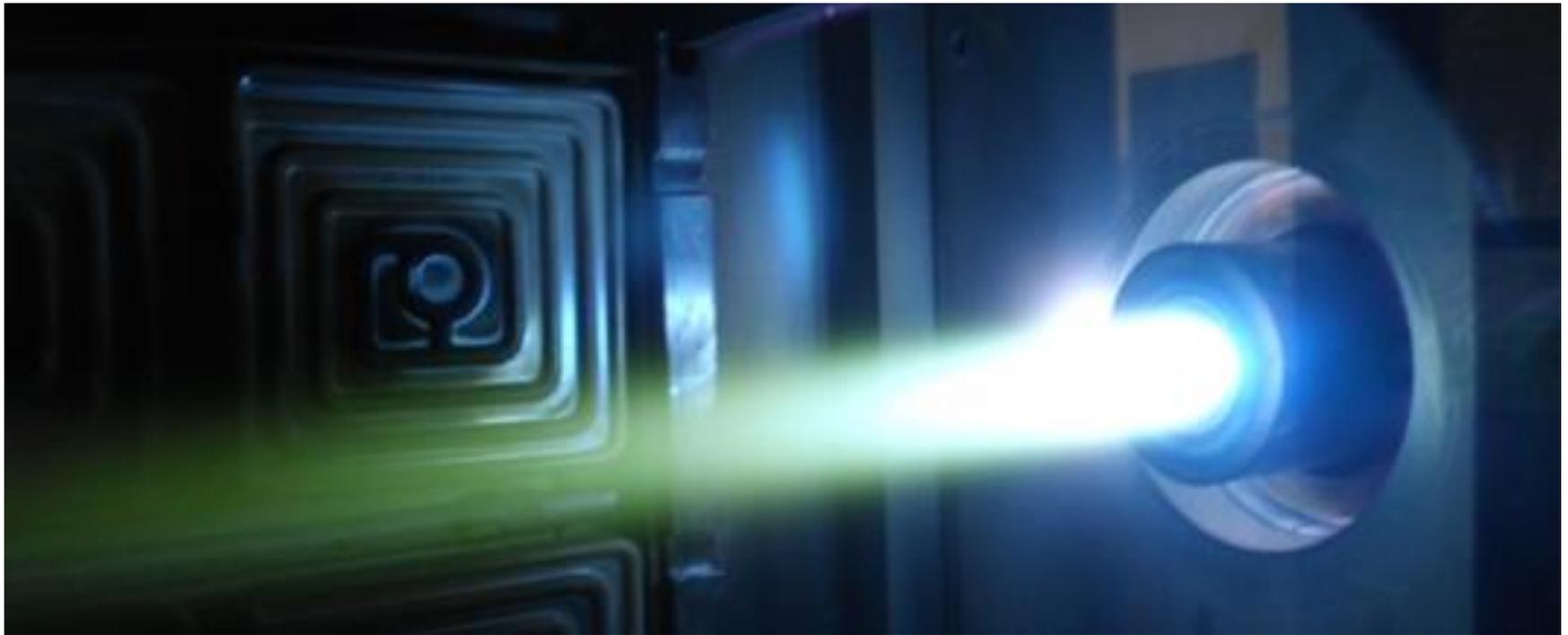


# SOME RECENT DEVELOPMENTS IN SPUTTER TECHNOLOGY

G. Bräuer, R. Bandorf, M. Keunecke, A. Pflug, B. Szyszka, V. Sittinger,  
M. Vergöhl

[www.ist.fraunhofer.de](http://www.ist.fraunhofer.de)



# Outline

- Introduction
- HIPIMS – ready for industry?
- Sputter technology for optical coatings
- Hollow cathode based sputter processes
- What comes next?
- Summary

# Megatrends



- Climate Change
- Shortage of Resources
- Demographic Change
- Globalization

Images © Fraunhofer; Photocase

# What people need – Tomorrow's opportunities

Health

Communication

Safety

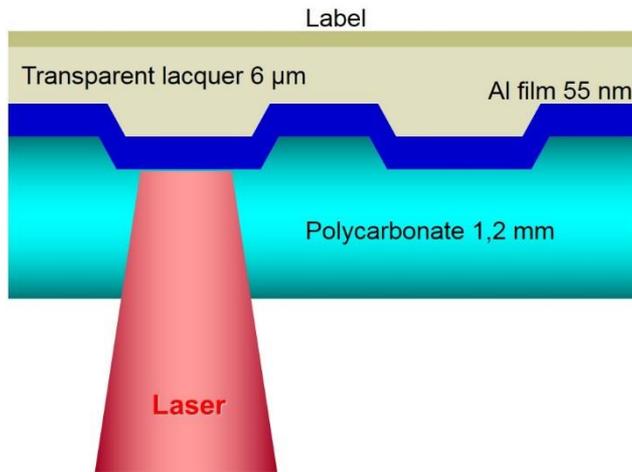
Energy

Mobility

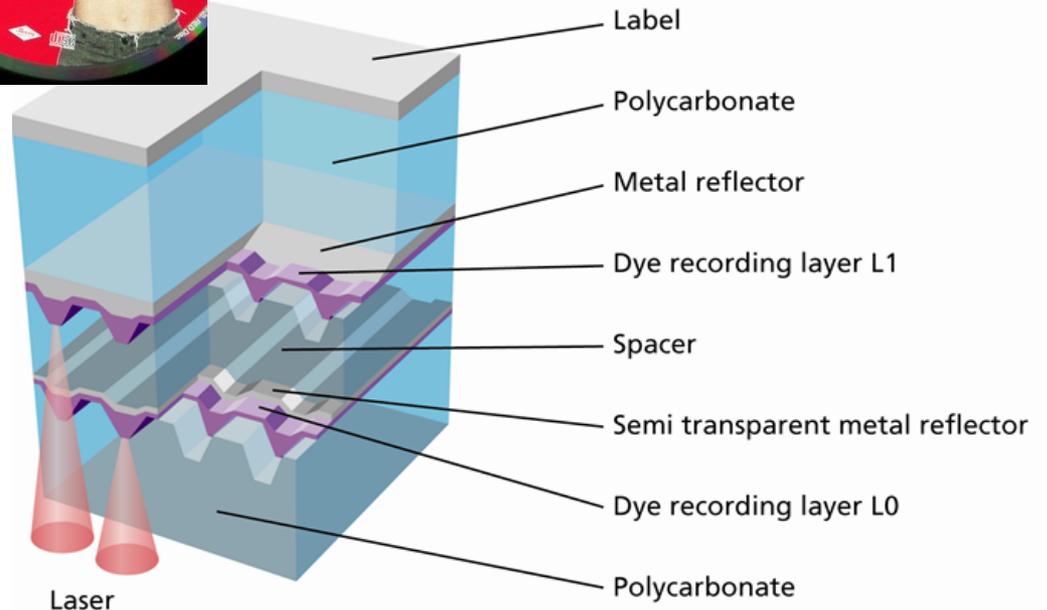
Environment

**SURFACE TECHNOLOGY  
IS ONE OF THE KEYS.**

# Innovations through thin films– increasing complexity



Compact Disc (~ 1982), 0.65 GB, read only



Dual Layer DVD (~ 2002), 9 GB, recordable

# Deposition rates for various coating technologies

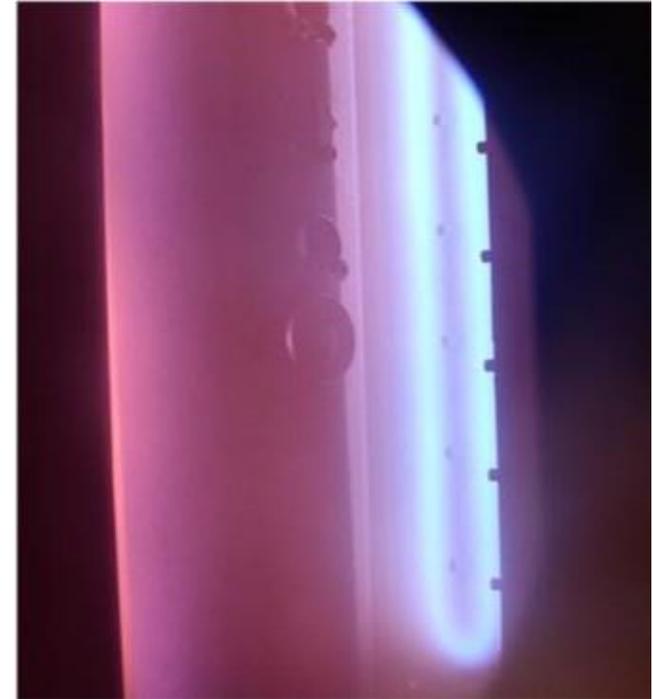
Technology	Deposition rate [nm/s]
Atomic Layer Deposition	0,1
Reactive pulse magnetron sputtering of TiO <sub>2</sub>	5
Reactive pulse magnetron sputtering of SiO <sub>2</sub>	5 – 10
Magnetron sputtering of metals	10 – 100
Plasmapolymerisation	10 – 100
Electron beam evaporation of metals	100 – 1.000
Thermal evaporation of metals	500 – 5.000
Electroplating of hard chrome	10 - 12
Electroplating of nickel	15 – 150
Atmospheric pressure plasma spraying	

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# What is HIPIMS?

- Plasma pulses with typical power from 1 MW up to 6 MW (“conventional”: 50 kW)
- Voltage: 1 – 2 kV  
Current: up to 4 MA
- Duty Cycle 1 – 3 %  
→ same mean power as for DC sputtering



Source: SVS Vacuum Coating Technologies

**➔ high amount (50 – 70 %) of ionized sputtered species forming high quality dense films**

# "Conventional" magnetron sputtering and HIPIMS plasma

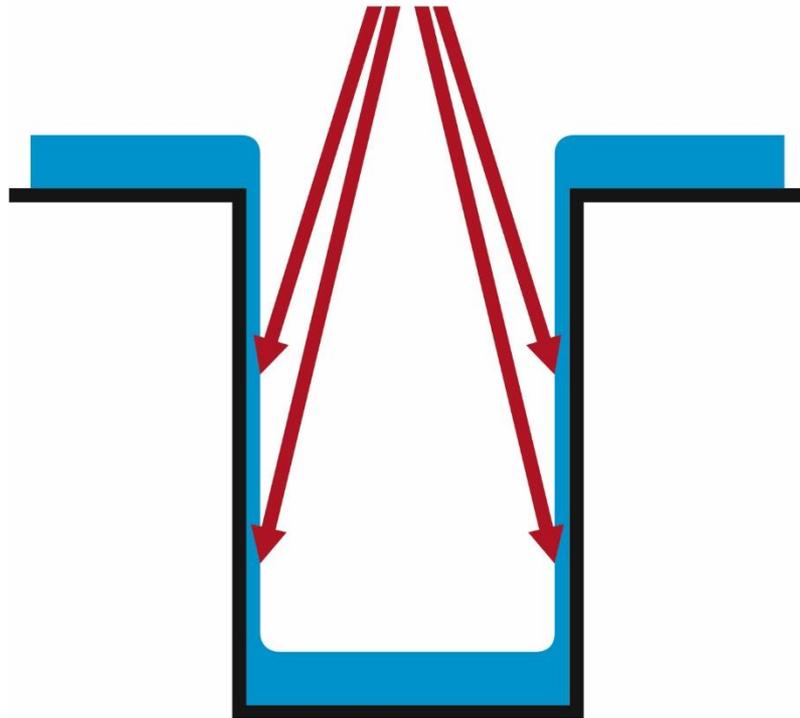


# Application fields of HIPIMS coatings

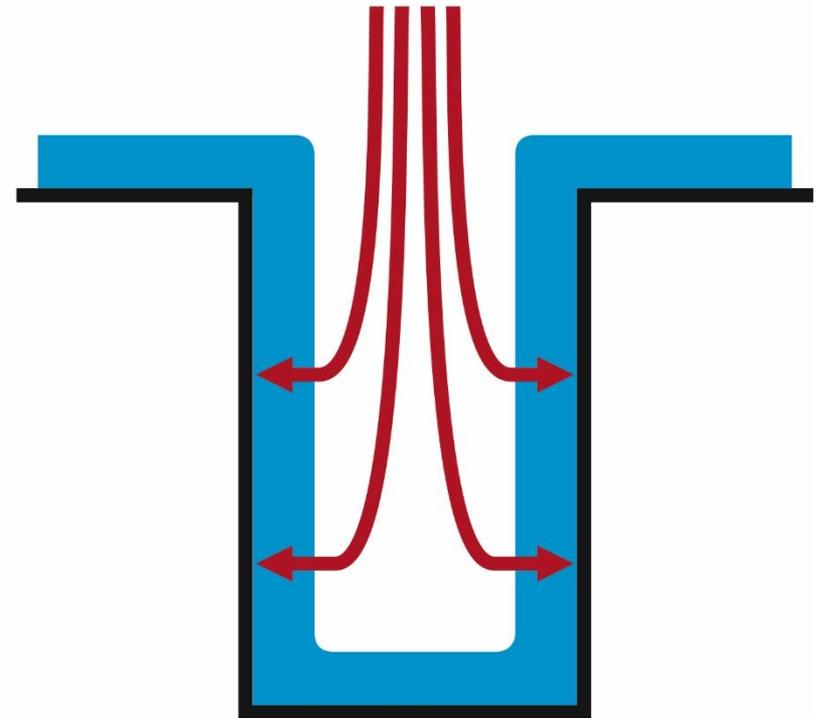
- Coating of 3D structures (filling of trenches)
- Hard coatings for tribological applications (e.g. TiAlN)
- Coatings for precision optics
- Glass coating, e.g. transparent conductive films
- Sensors

# Coating of 3D structures (trench filling)

Conventional: film forming species are mainly neutrals



HIPIMS: film forming species are mainly ions

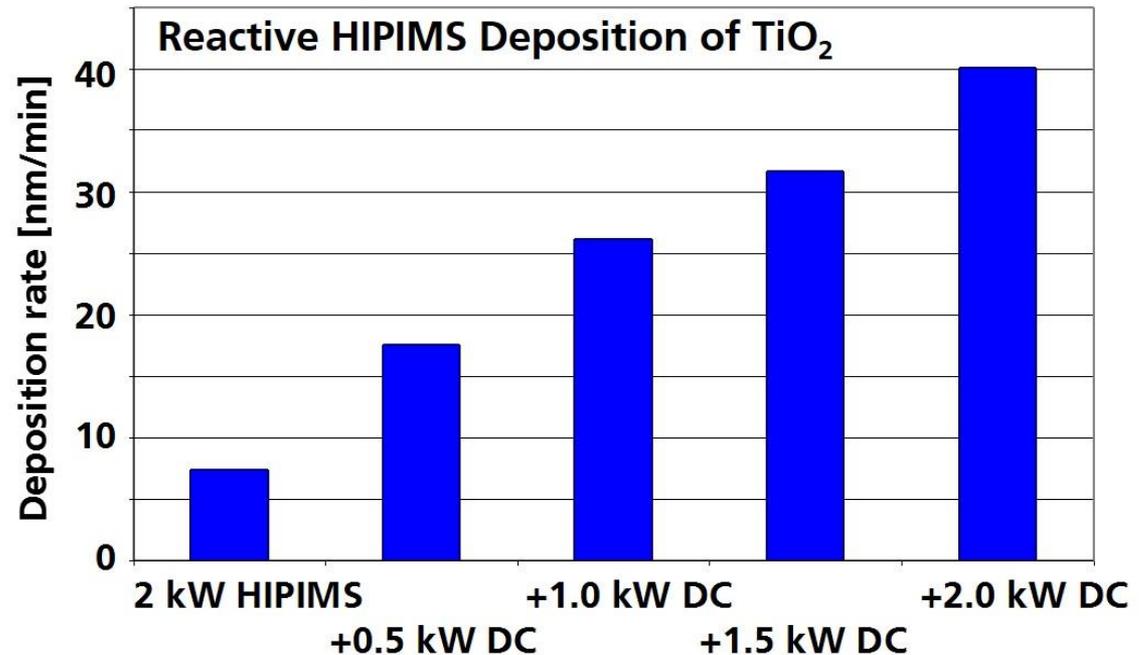


Source: Prof. Ulf Helmerson, Linköping University

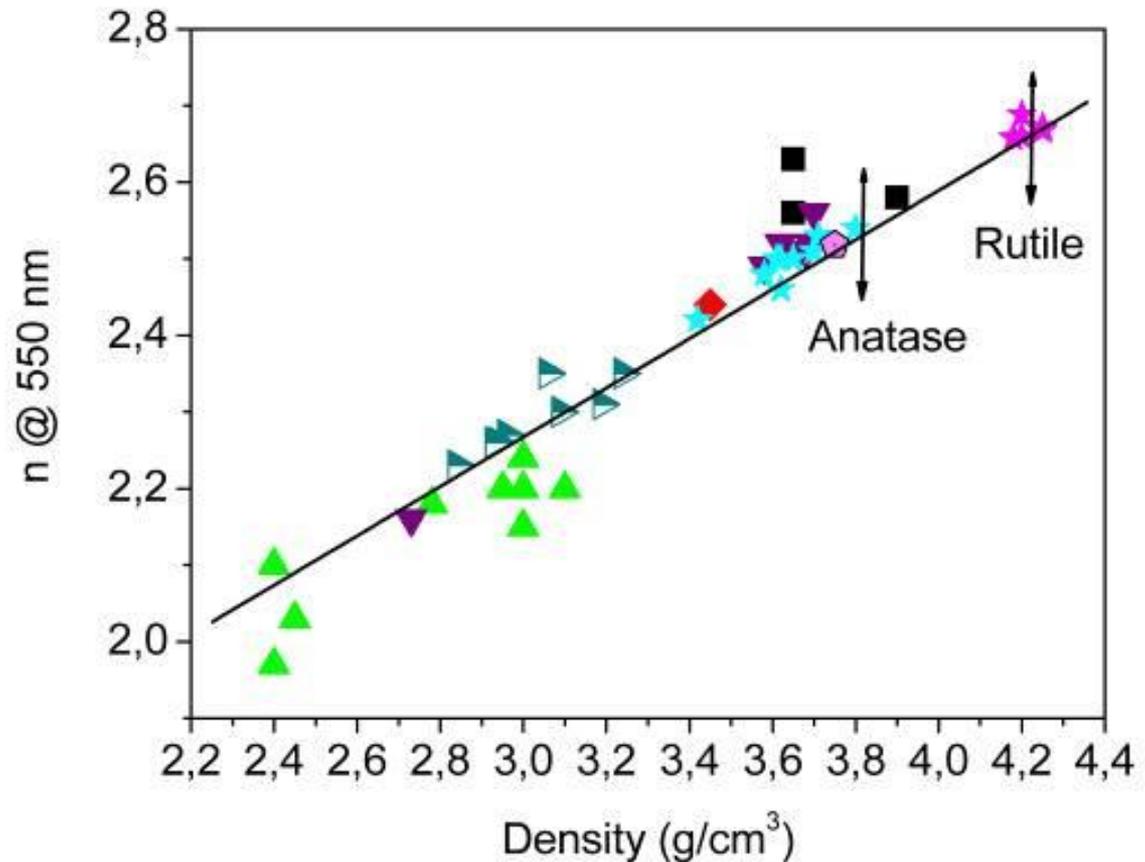
# Deposition rates for HIPIMS

Low deposition rates can be improved by adding DC.

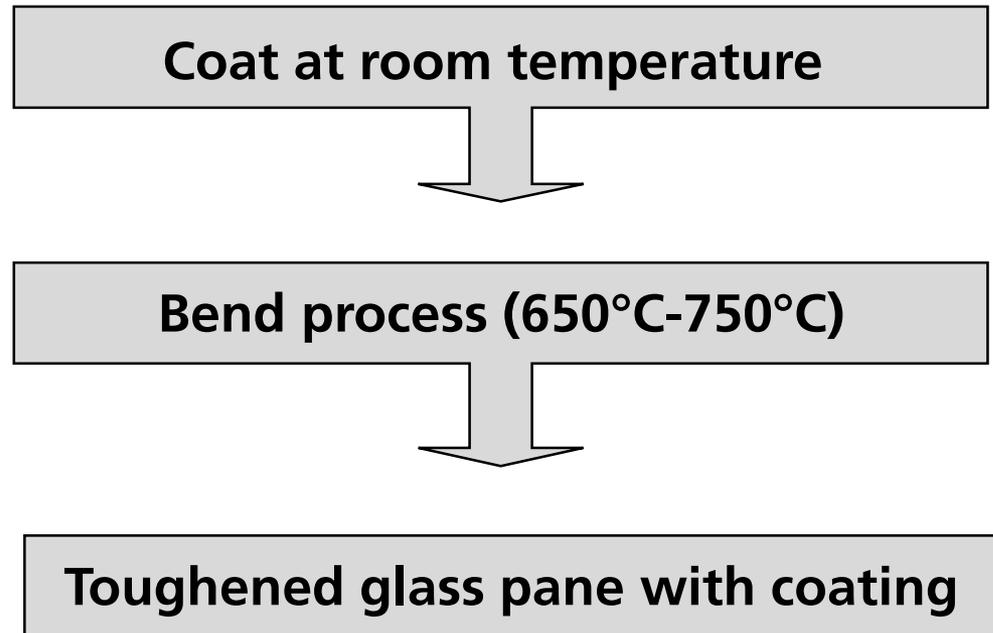
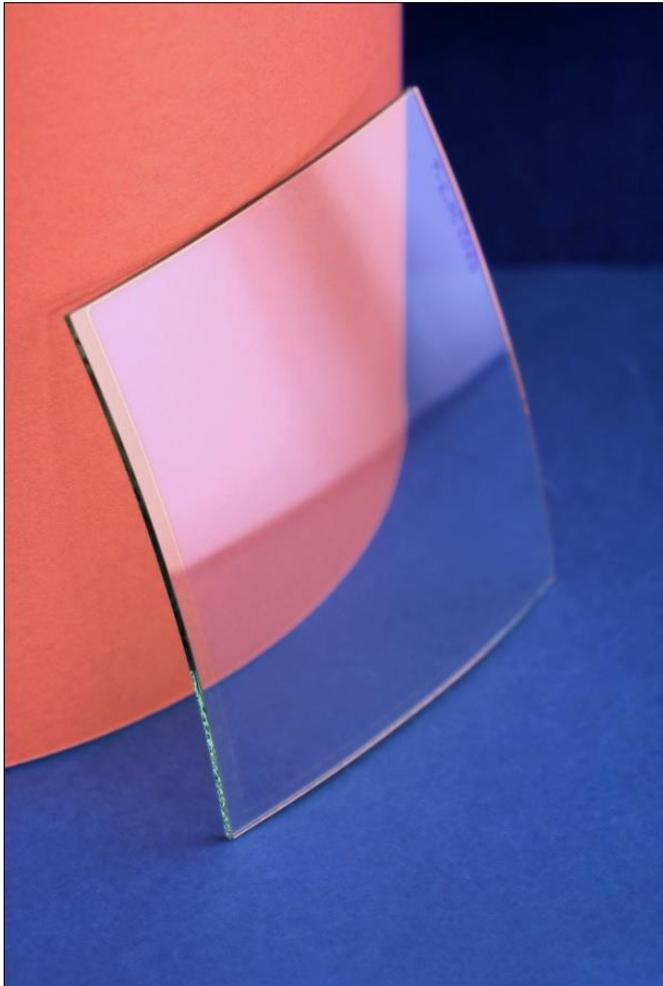
(Data taken from a planar magnetron 488 mm x 88 mm.)



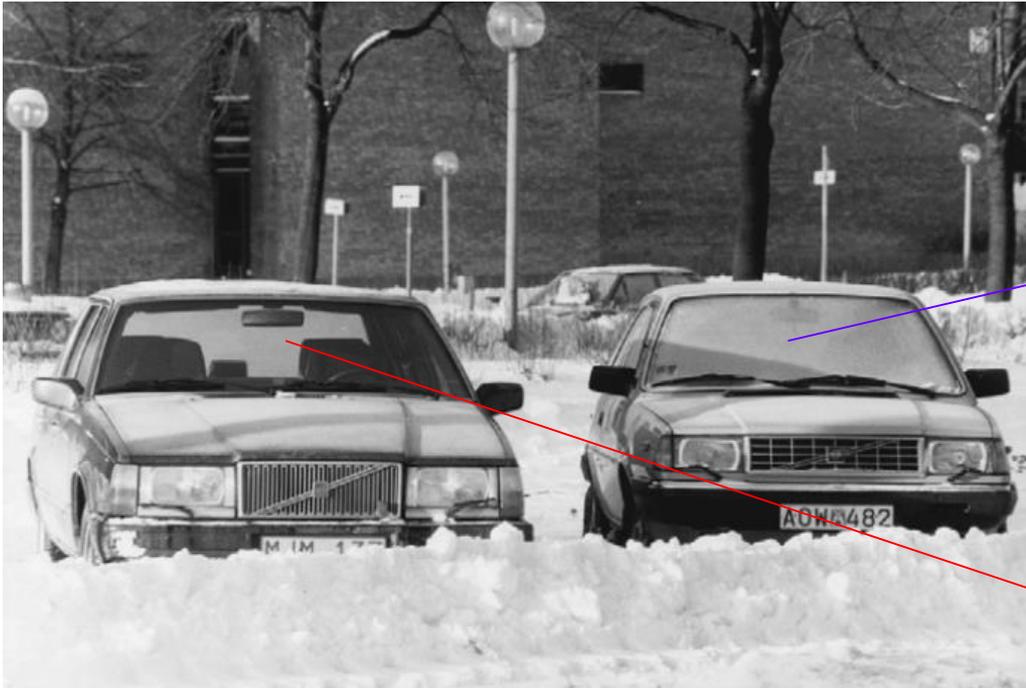
# TiO<sub>2</sub> deposition using various processes



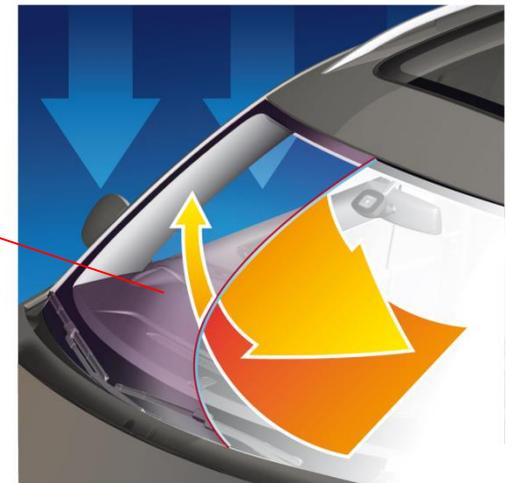
# HIPIMS ITO – coat and bend process for Low-E glass



# The ice-free windshield

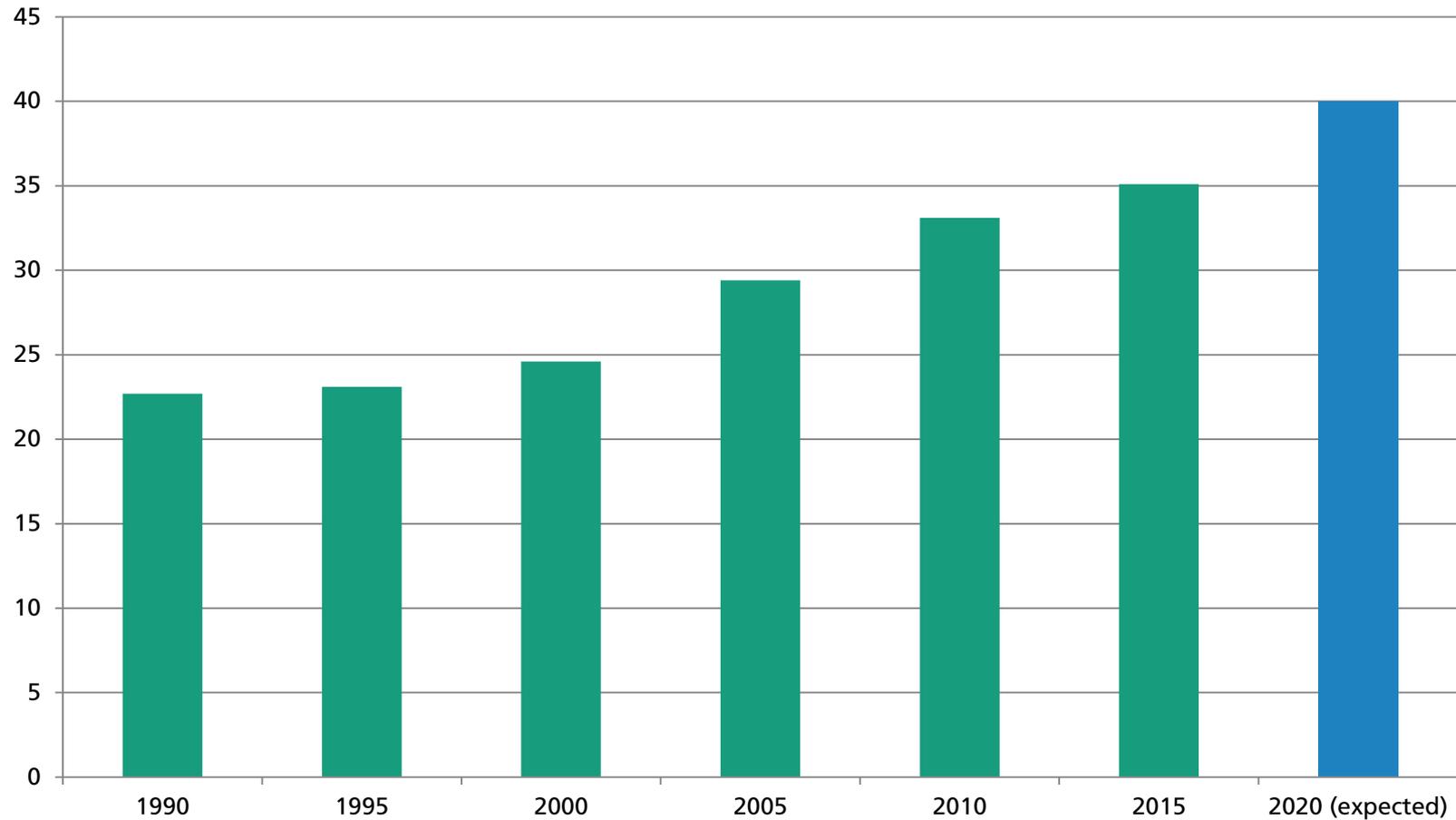


Source: Claes G. Granqvist, Transparent conductors as solar energy materials: A panoramic review, *Solar Energy Materials & Solar Cells* 91 (2007) 1529 - 1598



# Increasing CO<sub>2</sub> emissions

Global CO<sub>2</sub> emission in 10<sup>9</sup> tons



# Challenge: CO<sub>2</sub> reduction by friction reduction

## Effects of the different parameters influencing fuel consumption and CO<sub>2</sub> emission in passenger cars can be summarized as:

10 % mass reduction	⇒ 8.3 %	reduction in energy demand
10 % rolling resistance reduction	⇒ 2 %	reduction in energy demand
10 % frontal area reduction	⇒ 2.2 %	reduction in energy demand
5 % speed reduction	⇒ 6 %	reduction in energy demand
<b>5 % mechanical loss reduction</b>	<b>⇒ 1.5 %</b>	<b>reduction in energy demand</b>

Global fuel consumption for passenger cars 2009:  $63 \cdot 10^{10}$  liter (gasoline + diesel)

**→ 1,5 %:  $9,5 \cdot 10^9$  liter →  $23 \cdot 10^6$  t CO<sub>2</sub>**

Source: K. Holmberg, P. Andersson, A. Erdemir, *Global energy consumption due to friction in passenger cars*, Tribology International 47 (2012) 221.

**→ need for tribological optimized solutions**

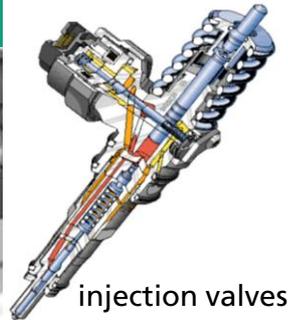
# DLC coatings – From research to markets

- Cutting tools
- Forming / Moulding
- Automotive / Racing
- Medical
- Decorative
- Sensors

# Application of a-C:H and a-C:H:Me



bucket tappets



injection valves

Automotive components

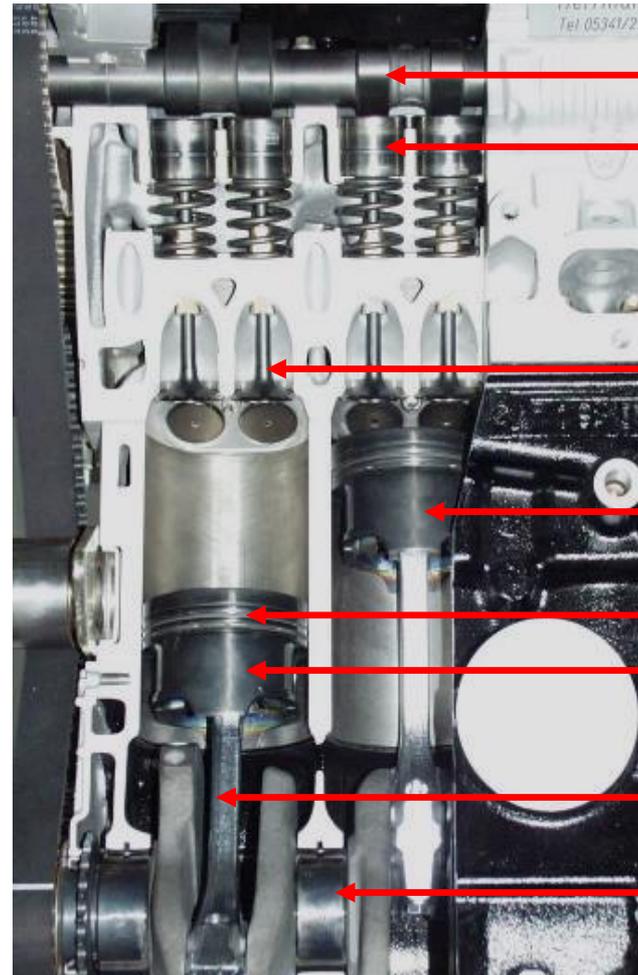
High performance applications (Car Racing)

Mass volume production DLC

Mass volume other coatings



piston pin



camshaft

tappet

valve

piston

piston ring

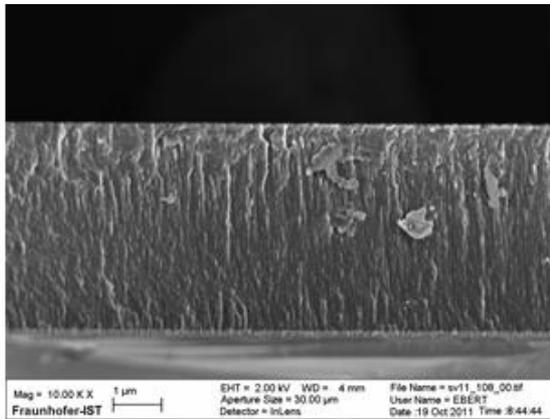
piston pin

drive rod

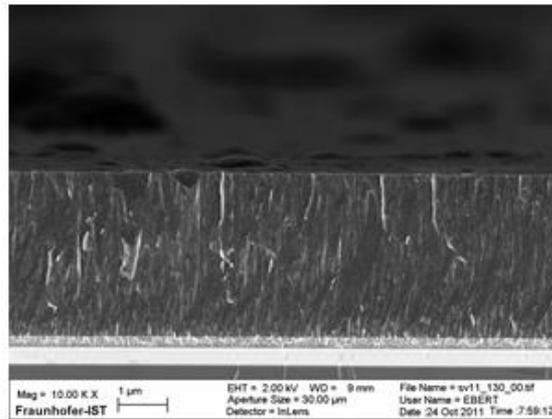
crankshaft

# DLC films deposited with reactive HIPIMS

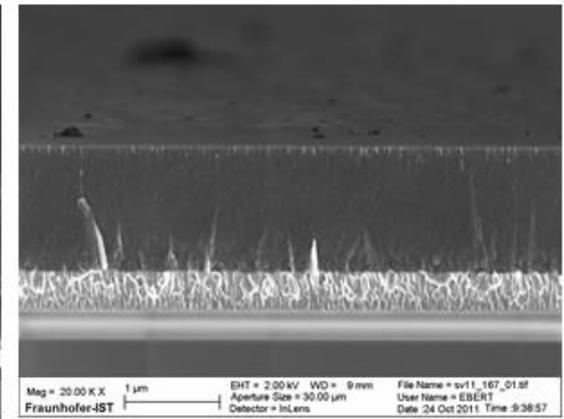
## Graphite Target, gas mixture of Ar, Ne, C<sub>2</sub>H<sub>2</sub>



0% C<sub>2</sub>H<sub>2</sub>, 15 GPa



4% C<sub>2</sub>H<sub>2</sub>, 28 GPa



5% C<sub>2</sub>H<sub>2</sub>, 53 GPa

# Outline

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# What means »precision« in precision optics?

1980

2 – 3 % tolerance, 50+ layers

late 1990

< 1% tolerance, 100+ layers

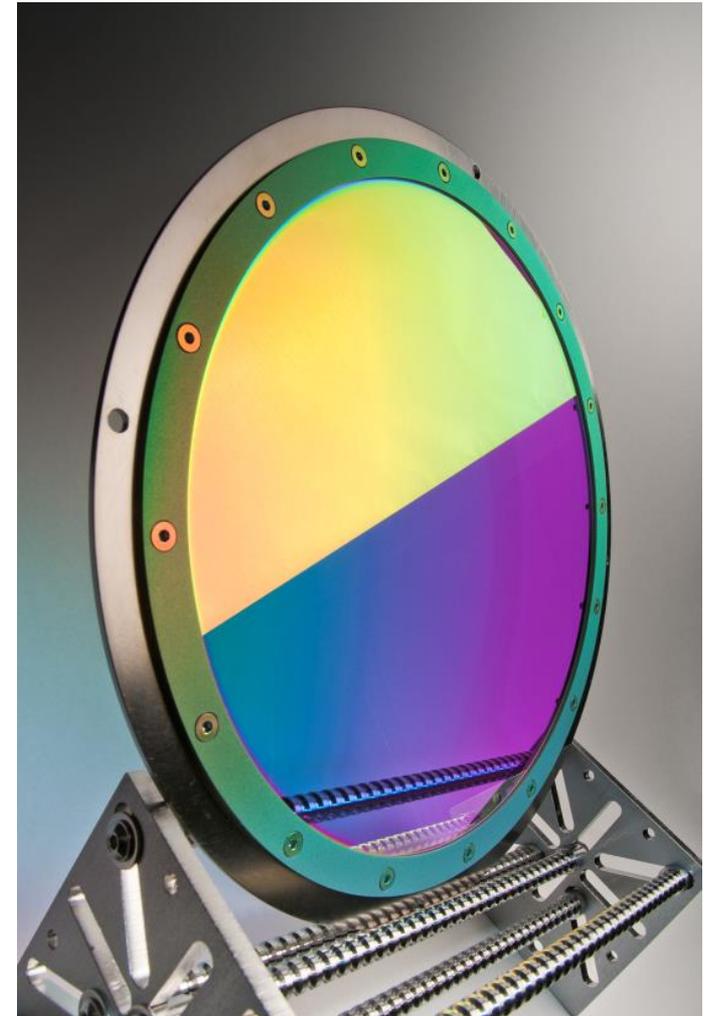
JDSU 2012

~ 0.5% ( $\pm 0.25\%$ ), 75 – 1000 layers  
world record (JDSU): **4410 layers**

Fraunhofer IST 2014

~ 0.2% ( $\pm 0.1\%$ ), 100+ layers

*(Georg Ockenfuss, ICCG9, Breda 2012)*



# Magnetron sputtering as emerging deposition process for precision optics

## Established:

evaporation  
high rate  
limited performance

## »high end«:

ion beam sputtering  
low rate  
high performance

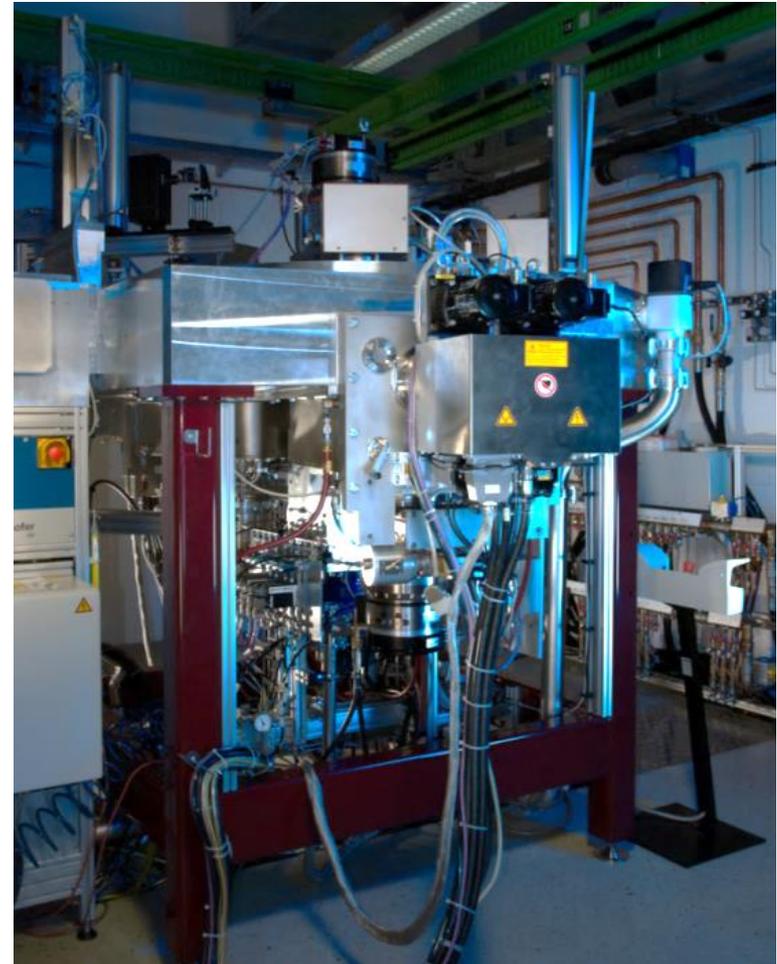
## emerging:

magnetron sputtering  
high rate  
high performance

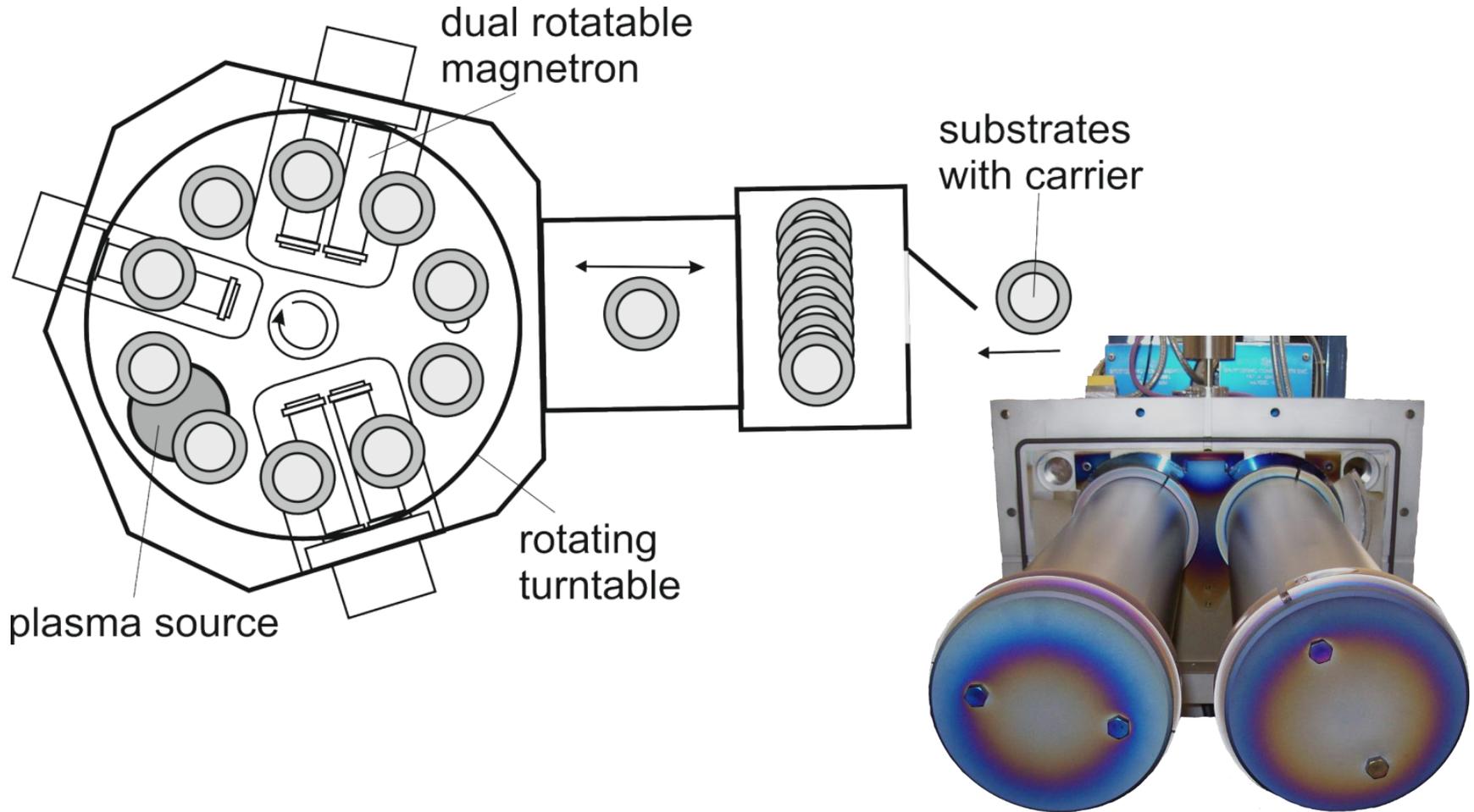
# EOSS<sup>®</sup> – Enhanced Optical Sputter System

## Main Features

- dual cylindrical magnetrons
- batch size: 10 substrates with Ø 200 mm
- fast turntable 250 rpm
- sputtering in metallic (with post oxidation) or reactive mode
- full optical control and process automation

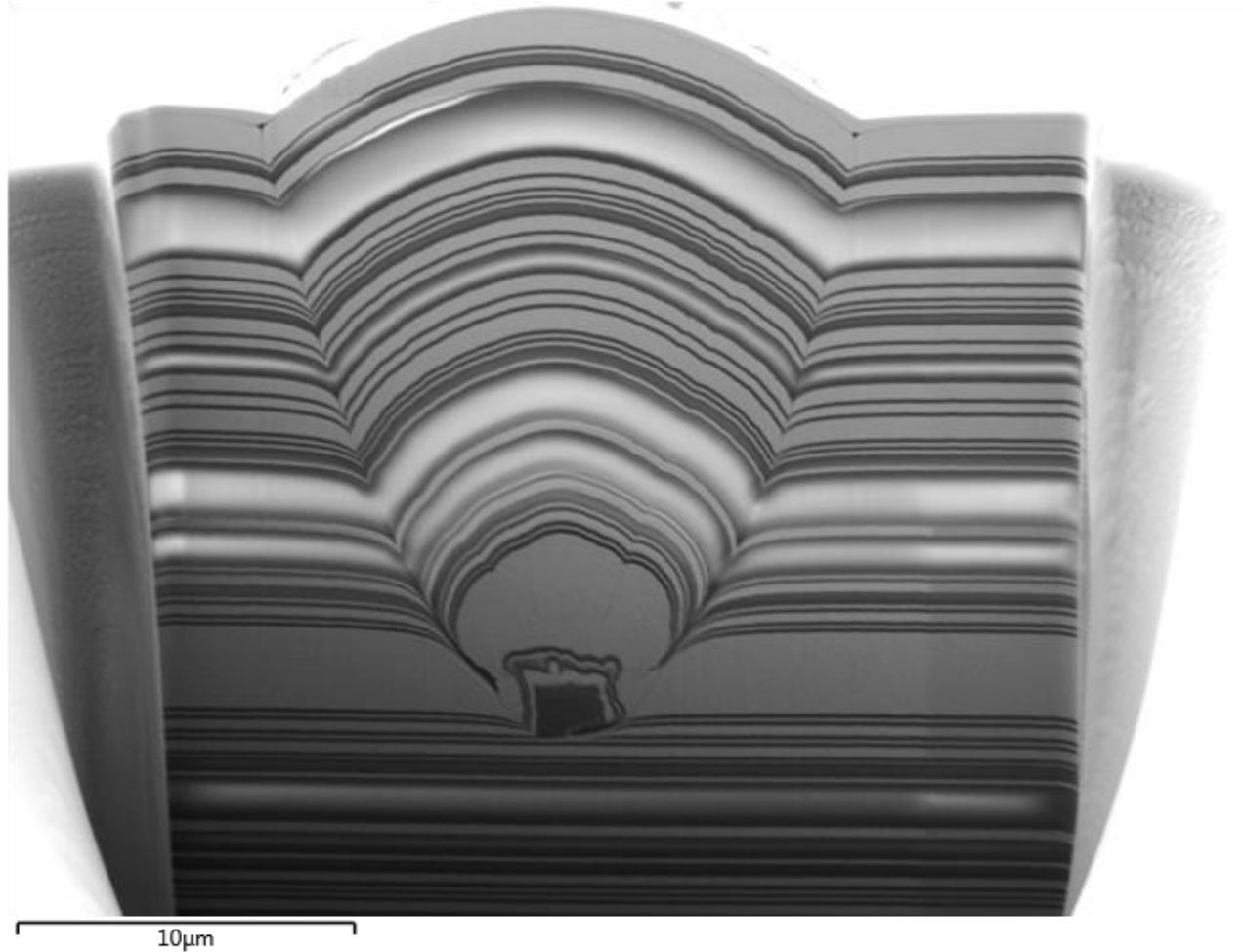


# EOSS<sup>®</sup> – Enhanced Optical Sputter System Setup at Fraunhofer IST



# Cross fraction of a multilayer stack with included defect

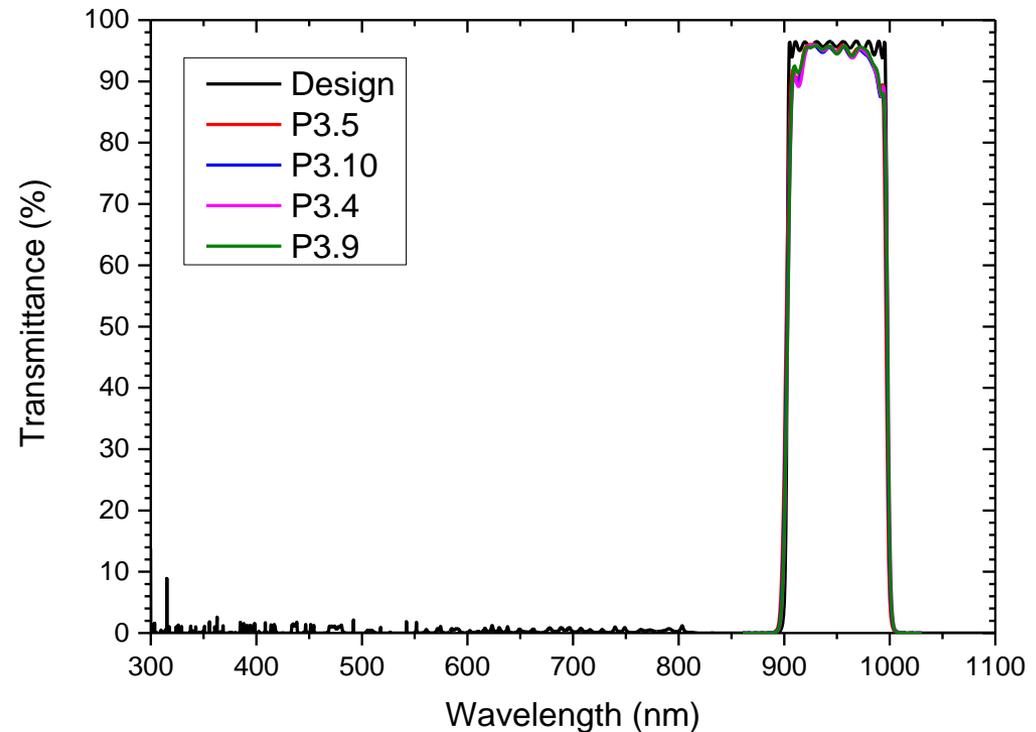
Elektronenbild 11



# Precision optics made on EOSS®

## Example: Bandpass filter for space mission

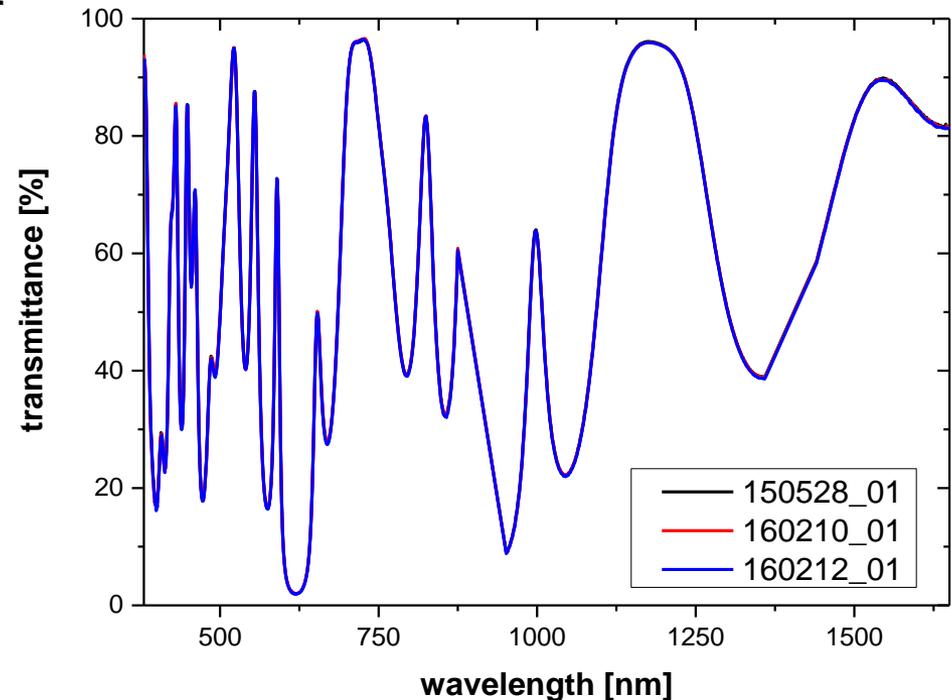
- IR bandpass filter
  - 137 layers
  - 14 μm total thickness
  - Ta<sub>2</sub>O<sub>5</sub>/SiO<sub>2</sub>
  - Single side coating
- Broad blocking range 300-1100 nm
- Central wavelength tolerance 0,3% over several substrates
- High transmittance
- Space qualified



# Precision optics made on EOSS®

## Example: Test of process stability

- Spectrum shows back side coating of a customer's filter
- 3 runs within 9 months (incl.: 1 new target)
- Test glasses had:
  - 18 layers
  - 3,6 µm thickness
- No visual difference in spectra
- Demonstrates the extremely high stability of refractive index and deposition rate



# Precision optics made on EOSS®

## Example: Antireflective coating on aspherical lenses

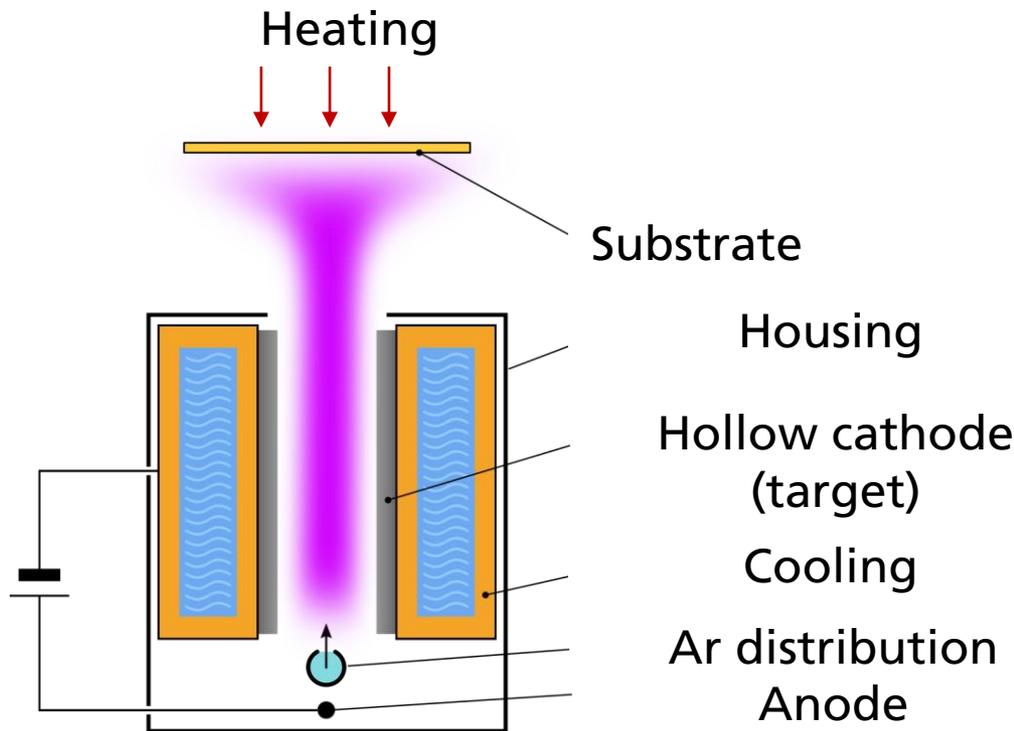
- Industrial application in retina scanners
- Strongly bended substrates
- Broad band AR in a wide range of angles required
- Complex stack: more than 50 layers
- Evaporation at its limit

# Outline

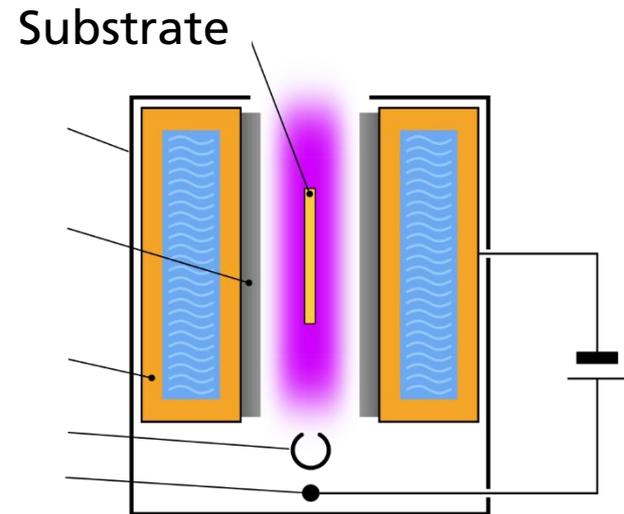
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# Gas Flow Sputtering (GFS) and Inner Hollow Cathode Sputtering (IHC)

## ■ Schematic GFS-Process



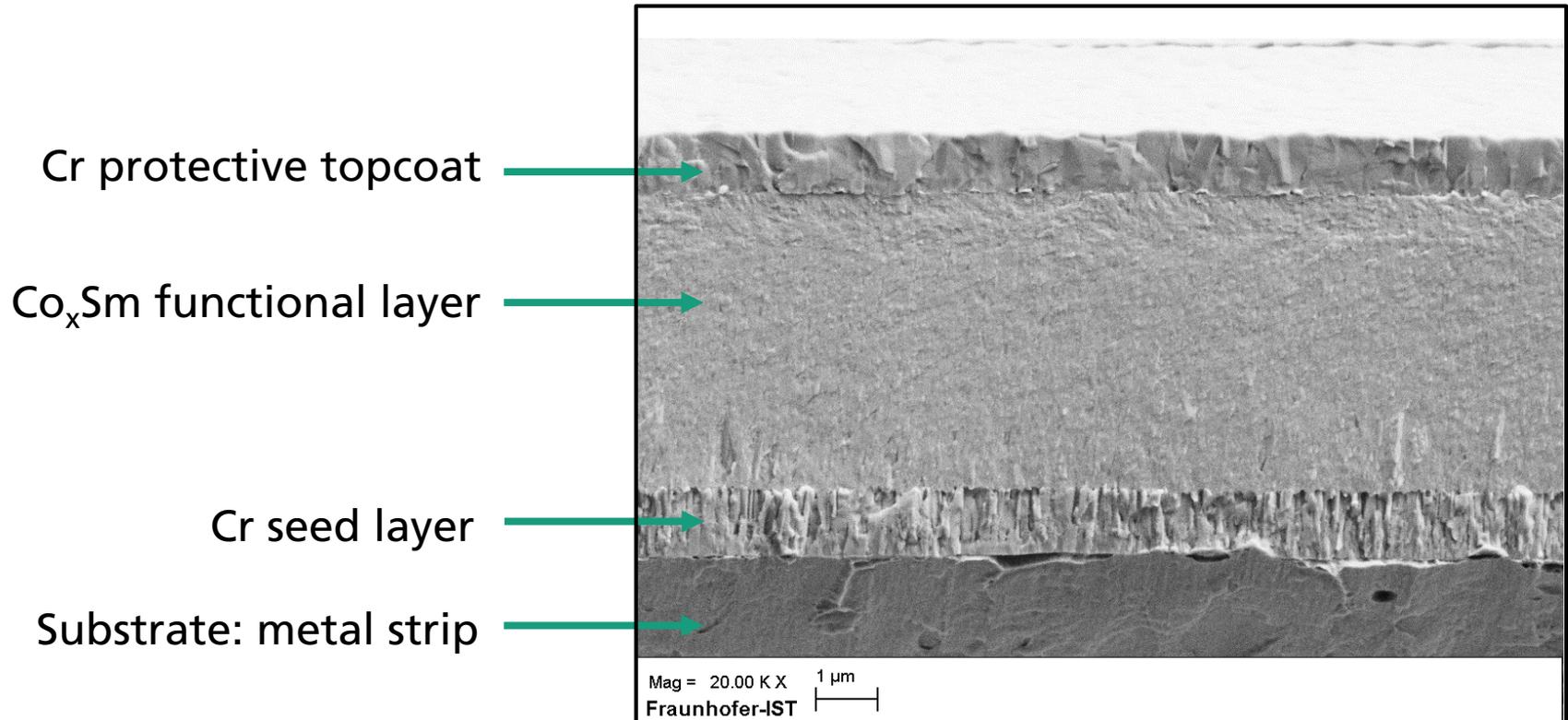
## ■ Schematic IHC-Process



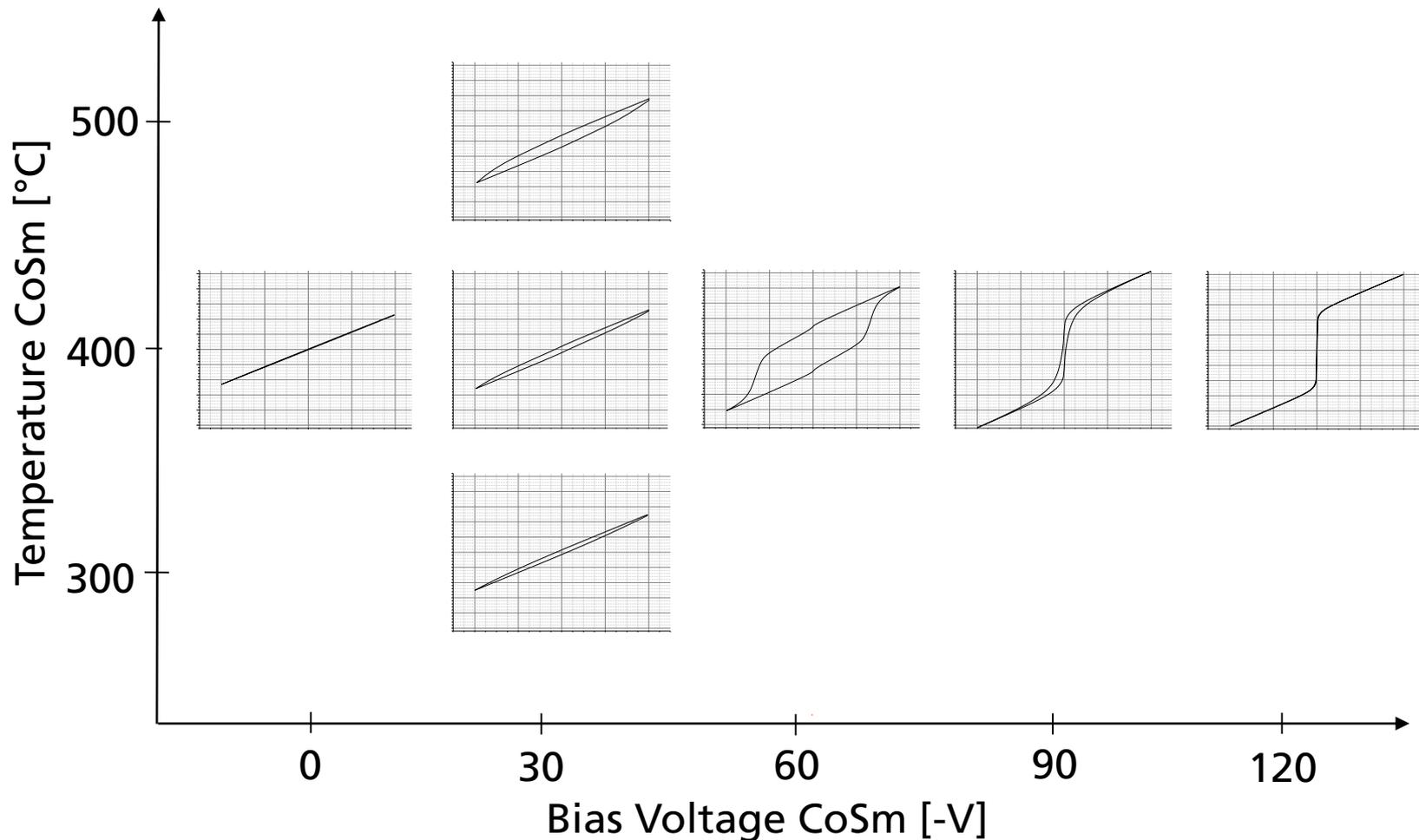
# Example for technical application of magnetic thin films

- Use of magnetic thin films for high precision positioning systems
  - Compact
  - Insensitive against dust/contaminations
  - Resolution in the nanometer regime
  - Absolute positioning in the micrometer range
    - High demand on the fabricated magnetic thin films

# Magnetic multilayer system made by GFS

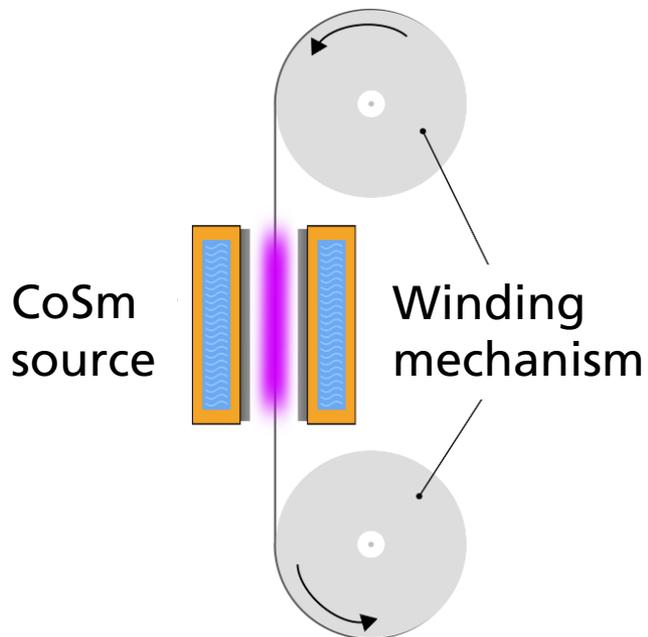


# GFS: Magnetic hysteresis behaviour for different substrate temperatures and bias voltages

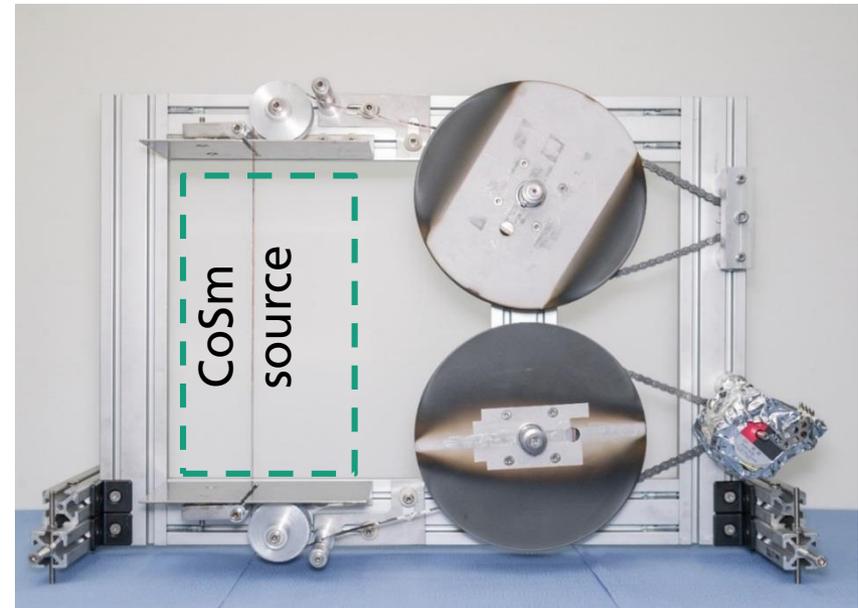


# Dynamic IHC: Pilot production

- Schematic of the setup for the dynamic deposition

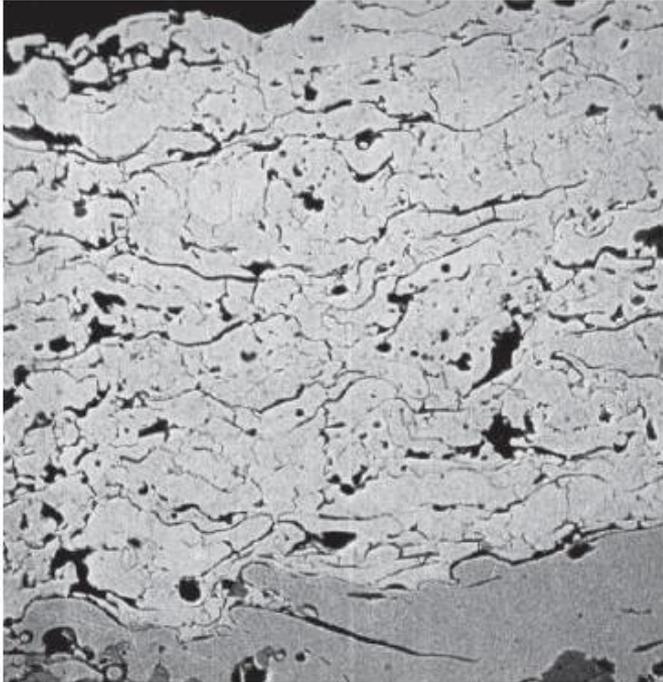


- Reel-to-reel setup (driven by a stepper motor)

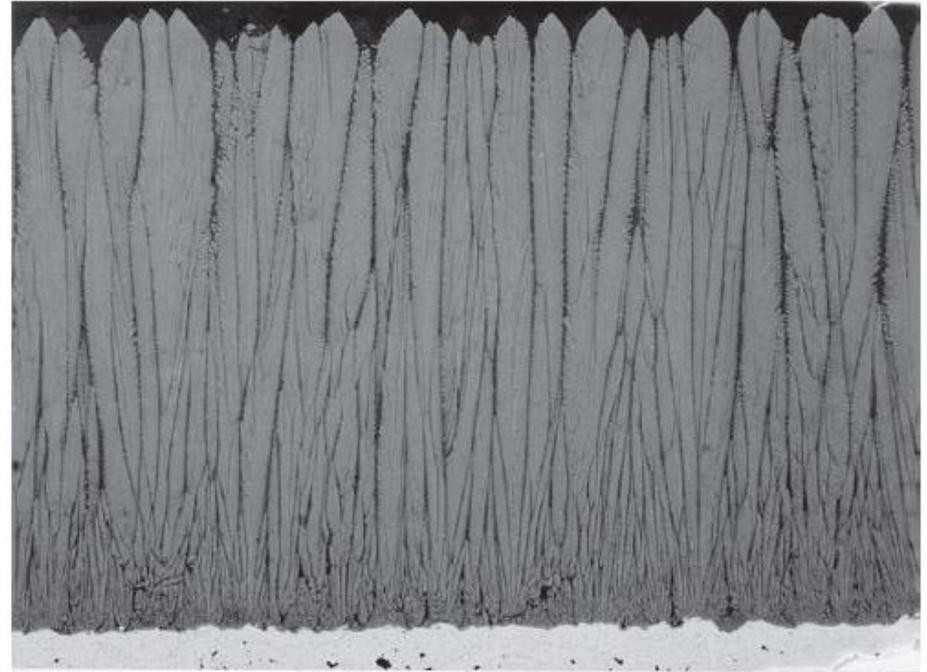


# Thermal barrier coatings produced by GFS

## Material: partly Y stabilized $ZrO_2$ (PYSZ)



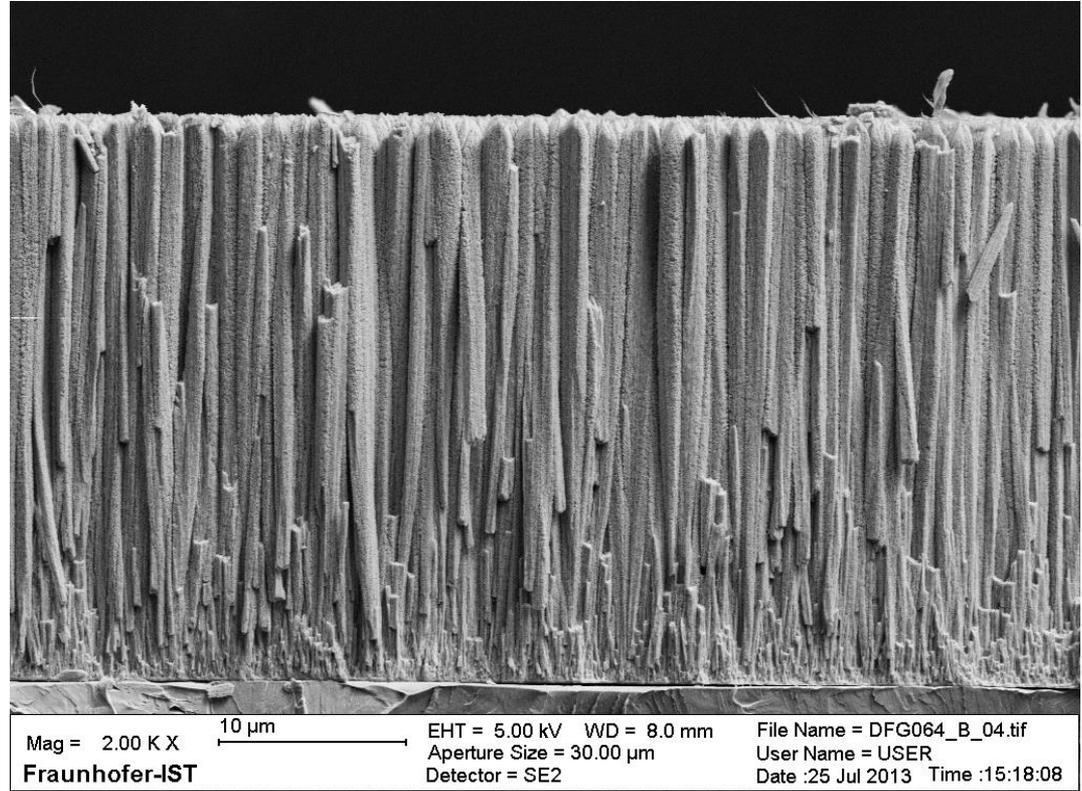
Deposition by Thermal Spraying → porous structure



Deposition by Electron Beam Evaporation (EBPVD) → columnar structure

Source: Nicholls et al., Surf. Coat. Technol 151 (2002), 383

# Deposition of thermal barrier coatings by GFS



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# Main R+D efforts in magnetron sputtering during the past 35 years

- Improvement of target material utilization
- Stabilization of the reactive process in the transition regime
- Long term stable high rate deposition of dielectric films
- Improved film properties through HIPIMS
- Higher deposition rates

# Magnetron sputtering through five decades

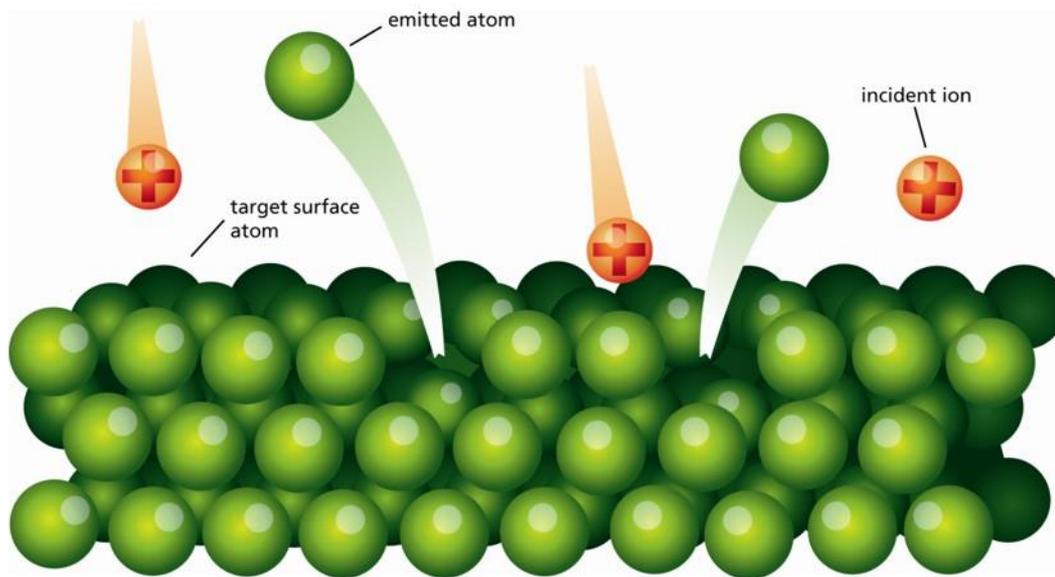
- The 1980s: The decade of **reactive DC sputtering**
- The 1990s: The decade of **pulsed sputtering** and **higher target utilization**
- The 2000s: The decade of **higher ionization**
- The 2010s: The decade of **higher ionization** and **higher precision**

## What comes next?

- The 2020s: The decade of **higher efficiency?**

# The sputter yield

$$\text{Sputter Yield } Y = \frac{\text{number of emitted target atoms}}{\text{number of incident ions}}$$



Yield depends on:

$E_0$  ion energy

$M_1$  ion mass

$M_2$  mass of target atom

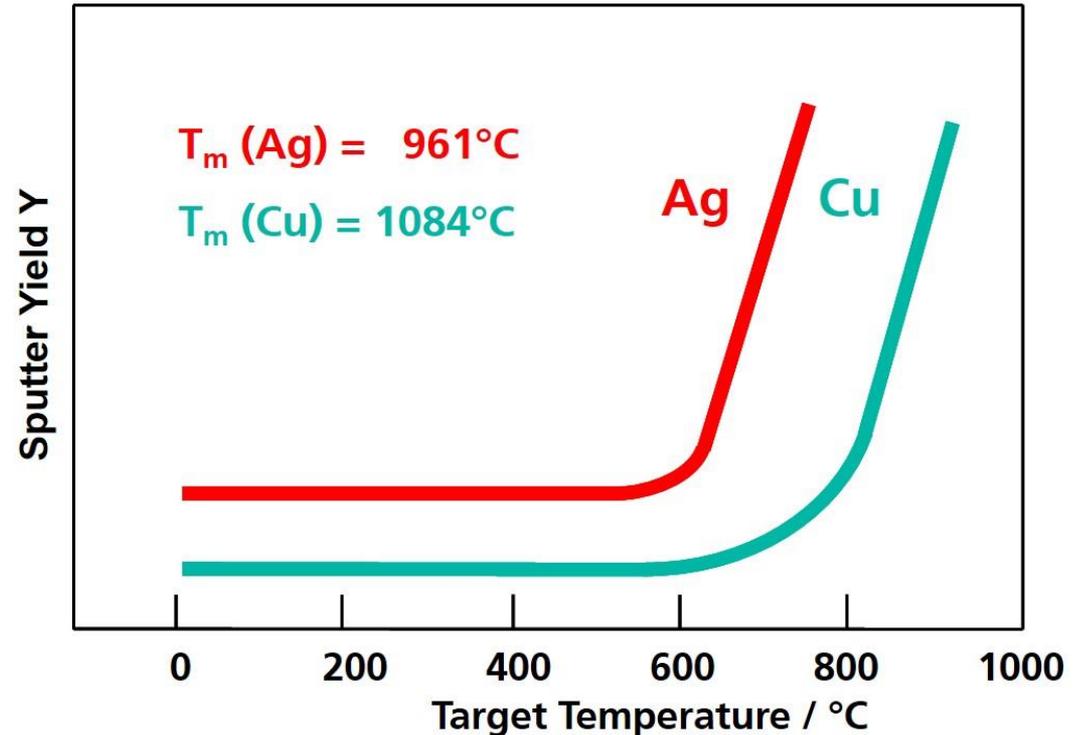
$U_0$  surface binding energy of target atom

$\Theta$  angle of ion incidence

$T$  target temperature

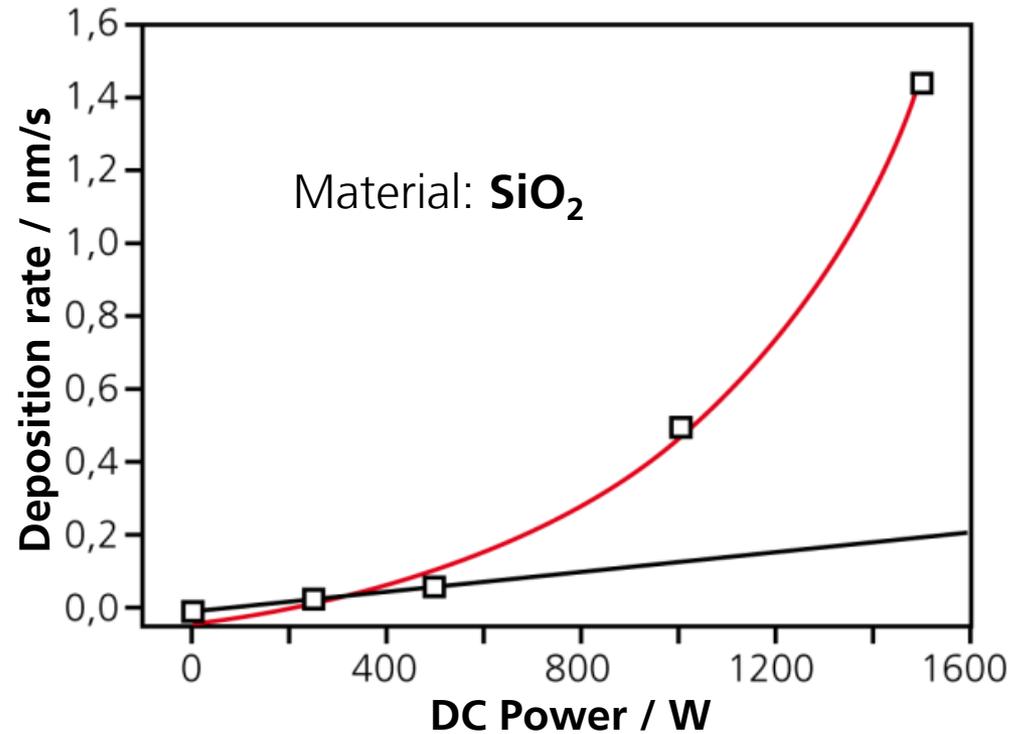
# The temperature dependence of the sputter yield

At  $T \sim 0.8 T_m$   
 ( $T_m$  = melting point)  
 Y increases  
 substantially due to  
 the formation of  
 „thermal spikes“.



R. A. Haefler: *Oberflächen- und Dünnschichttechnologie*  
 (Teil 1: Beschichtungen von Oberflächen), Springer Verlag, 1987

# Sputtering from hot targets (HTS)



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# Summary

The manufacturers of hard coatings count on HIPIMS, but there is still a lot of work to establish the technology for glass coating.

Magnetron sputtering has entered the world of precision optics. In the near future large area optical coatings should be available at reasonable cost.

Hollow cathode based sputter processes have found niche markets, in particular when very thick coatings are required.

**With  $\eta \sim 2\%$  the efficiency of the sputter process is still much lower than the efficiency of a solar cell.**

# THANK YOU FOR YOUR ATTENTION!

